



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:  
Wang, et al.

Serial No.: 10/800,112

Confirmation No.: 8920

Filed: March 12, 2004

For: Method of Depositing an  
Amorphous Carbon Film for  
Metal Etch Hardmask  
Application

MAIL STOP AMENDMENT  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

§ Group Art Unit: 1765

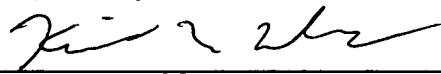
§ Examiner: Mahmoud Dahmene

CERTIFICATE OF MAILING 37 CFR 1.8	
I hereby certify that this correspondence is being deposited on <u>February 6, 2006</u> , with the United States Postal Service as First Class Mail in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.	
February 6, 2006	<u>Brian K. Hrma</u>
Date	Brian K. Hrma

STATEMENT OF COMMON OWNERSHIP

The present application (Serial No. 10/800,112; hereinafter the "Application"), and United States Patent Application Serial No. 10/438,638 (Patent Publication No. 2004/0229470), *Rui et al*, were, at the time the invention of the Application was made, owned by the same person, or subject to an obligation of assignment to the same person, Applied Materials, Inc.

Respectfully submitted,

  
Keith M. Tackett  
Registration No. 32,008  
PATTERSON & SHERIDAN, L.L.P.  
3040 Post Oak Blvd., Suite 1500  
Houston, TX 77056  
Telephone: (713) 623-4844  
Facsimile: (713) 623-4846  
Attorney for Applicant(s)